Theoretical Insights and Modeling of Vertical GaN Switches for Industrial Applications

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> > GaN

Bodo's Wide Bandgap Event 2024 Making WBG Designs Happen

Vertical GaN Transistors





GaN-based vertical transistors: (a) CAVET, (b) Trench MOSFET, (c) Fin FET and (d) JFET

CAVET : Current Aperture Vertical Electron





Conventional CAVET Structure

- Advantages
 - High channel conductivity due to 2DEG
 - High Breakdown Voltage
 - Reduced DC-RF Dispersion
 - Efficient Die Area Utilization

- Challenges
 - Leakage Paths
 - Device Design
 - Fabrication Technique
 - Achieving Normally-Off Operation

Vertical Trench MOSFET





>Advantages

Normally off

≻Challenges

- Doesn't utilize a 2DEG channel
- Low electron mobility
- Potential trapping effects
- Buried p-GaN Layer Activation
- Potential punch-through breakdown issues
- Very high turn on voltage.

➢Application

• High power applications

Output Characteristics

• On-resistance decreases with the increase of the current aperture length.





The output characteristics for different aperture lengths at V_{GS} = 0 V

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Intrinsic Gate Capacitance





CAVET structure schematic with a simplified model of intrinsic gate capacitances

CV characteristics







Gate-drain Capacitance

 Gate-drain Capacitance increases with aperture length



RF characteristics

• The unilateral power gain increases with the aperture length.





- The value of $\sqrt{f_T \times f_{Max}}$ for large aperture length is higher than 2.4 GHz.
- The peak values of f_T and f_{MAX} are 0.09 GHz and 66.73 GHz, respectively, achieved at L_{CA} = 16 µm.

Switching Circuit





Switching test circuit using CAVET

Switching Waveforms and Energy loss



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Rectangular-wave oscillator circuit





(a) 1 MHz, (b) 20 MHz and (c) 100 MHz.

• Output waveform of oscillator remains sharp for larger aperture length at higher frequencies.



Schematic circuit diagram of a rectangular-wave oscillator circuit.

Figure of Merits





Comparison of Figure of Merits for various current aperture lengths of CAVET.

- Baliga's Figure of Merit (BFOM) is highest for medium aperture length while Switching Figure of Merit (FOM_{sw}) is highest for large aperture length.
- Considering this trade-off Device with aperture length of 15 µm is best for high power switching applications.



Design of Vertical GaN Device with Superior Performance than

Conventional Device

E-Mode Device





- By adjusting the parameters,
 - an **E-Mode device** can be

achieved.

Transfer Characteristics of Conventional and proposed Device at logarithmic Scale

Optimization of On-state Resistance

• On- Resistance :

The conventional device is 2.22 m Ω .

The proposed device is $1.88 \text{ m}\Omega$.



Breakdown Voltage Characteristics



RF Characteristics

• Proposed device achieves a higher Unilateral power gain





- For proposed device, the f_T and f_{MAX} values increase more than 15 and 10 times respectively.
- The $\sqrt{f_T \times f_{Max}}$ value increases almost 20 times.

Switching Characteristics





Figure of Merits





 The Baliga's Figure of Merit (BFOM) and Switching Figure of Merit (FOM_{SW}) both are higher for proposed device than the Conventional Device.





Faricated GaN Vertical Trench MOSFET

- The active area of the fabricated device is around $5.88 \times 10^{-4} cm^2$.
- The threshold voltage is around 10 V.
- The current density around Vgs=11V is 1.5 kAcm-2
- The on-state resistance is $5.8m\Omega cm^2$
- And the breakdown voltage of the device is 1.6kV.

M. Kamiński, A. Taube, J. Tarenko, O. Sadowski, E. Brzozowski, J. Wierzbicka, M. Zadura, M. Ekielski, K. Kosiel, and J. Jankowska-Śliwińska, "Vertical GaN Trench-MOSFETs Fabricated on Ammonothermally Grown Bulk GaN Substrates," physica status solidi (a), pp. 2400077, 2023.

Vertical Trench MOSFET (Simulated)



Simulated GaN Vertical Trench MOSFET with meshing





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